

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPLICANTS: Jaehwan EUN, et.al.

SERIAL NO. : to be assigned

FILED : herewith

FOR : METHOD FOR PREPARATION OF FERROELECTRIC SINGLE  
CRYSTAL FILM STRUCTURE USING DEPOSITION METHOD

EXAMINER: to be assigned

GROUP: to be assigned

Attention: Intial Patent Examination Division  
Commissioner for Patents  
PO Box 1450  
Alexandria, VA 22313-1450

PRELIMINARY AMENDMENT

Sir:

Prior to examination, it is respectfully requested that claims 10 and 15  
in the present application be amended.